



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Chunyuan Chao, Kuei-Chang Tsai and George A. Kovall  
Assignee: Mosel-Vitelic, Inc.  
Title: Dynamically Controllable Reduction of Vertical Contact Diameter Through Adjustment of Etch Mask Stack for Dielectric Etch  
Application No.: 10/718,320 Filing Date: 11/19/2003  
Examiner: Deo, Duy Vu Nguyen Group Art Unit: 1765  
Docket No.: M-15208 US Confirm No.: 1058

San Jose, California  
October 19, 2006

Mail Stop RCE  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

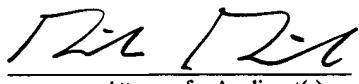
**PETITION FOR EXTENSION OF TIME**

Dear Sir:

Applicants respectfully petitions for a two-month extension of time within which to file the Response to the Office Action mailed on May 19, 2006 thus allowing the undersigned until October 19, 2006.

Please charge the amount of \$450.00 set forth in the enclosed transmittal letter.

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on October 19, 2006.

  
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Attorney for Applicant(s)      Date of Signature  
10-19-06

Respectfully submitted,



Gideon Gimlan  
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